

Amendments to the Claims

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

- 1 1. (Original) A magnetic field sensor for sensing an applied magnetic field, the
2 sensor comprising:
3 a layer of magnetostrictive material having a magnetization vector that
4 responds to the applied magnetic field by rotating in a plane and generating a
5 stress;
6 a layer of electroactive material, mechanically bonded to the layer of
7 magnetostrictive material, that responds to the stress by generating a voltage; and
8 electrodes that measure the voltage generated by the electroactive
9 material in a direction substantially parallel to the plane in which the magnetization
10 vector rotates.
- 1 2. (Currently amended) The sensor of claim 1 wherein the magnetostrictive material
2 is selected from the group consisting of amorphous-FeBSi, FeCoBSi alloys,
3 polycrystalline nickel, iron-nickel alloys, iron-cobalt alloys and TbDyFe alloys
4 Terfenol-D®.
- 1 3. (Currently amended) The sensor of claim 2 wherein the magnetostrictive material
2 is selected from the group consisting of $\text{Fe}_x\text{B}_y\text{Si}_{1-x-y}$, where $70 < x < 86$ at%, $2 < y$
3 < 20 , and $0 < z = 1-x-y < 8$ at%, $\text{Fe}_x\text{Co}_y\text{B}_z\text{Si}_{1-x-y-z}$ where $70 < x+y < 86$ at% and y is
4 between 1 and 46 at%, $2 < z < 18$, and $0 < 1-x-y-z < 16$ at%, polycrystalline
5 nickel, iron-nickel alloys where Ni is between 40 and 70 at%, iron-cobalt alloys
6 where Co between 30 and 80%, and Terfenol-D® $\text{Fe}_2(\text{Dy}_{0.67}\text{Tb}_{0.33})$ alloys.
- 1 4. (Original) The sensor of claim 2 wherein the magnetostrictive material comprises
2 a composition near $\text{Fe}_{78}\text{B}_{20}\text{Si}_2$.

- 1 5. (Original) The sensor of claim 2 wherein the magnetostrictive material comprises
2 a composition near $\text{Fe}_{68}\text{Co}_{10}\text{B}_{18}\text{Si}_4$.
- 1 6. (Original) The sensor of claim 2 wherein the magnetostrictive material comprises
2 an iron-nickel alloy with substantially 50% Ni.
- 1 7. (Original) The sensor of claim 2 wherein the magnetostrictive material comprises
2 an iron-cobalt alloy with substantially 55% Co.
- 1 8. (Original) The sensor of claim 1 wherein the electroactive material is selected
2 from the group consisting of lead zirconate titanate ceramics ($\text{Pb}(\text{Zr}_x\text{Ti}_{1-x})\text{O}_3$),
3 polyvinylidene difluoride polarized polymers (PVDF), aluminum nitride (AlN),
4 quartz (SiO_x), ferroelectric materials, electrostrictive materials and relaxor
5 ferroelectric materials.
- 1 9. (Original) The sensor of claim 8 wherein the electroactive material is
2 electrostrictive material substantial of the form $(\text{Bi}_{0.5}\text{Na}_{0.5})_{1-x}\text{Ba}_x\text{Zr}_y\text{Ti}_{1-y}\text{O}_3$.
- 1 10. (Original) The sensor of claim 8 wherein the electroactive material is a relaxor
2 ferroelectric material substantially of the form $\text{Pb}(\text{Mg}_{1/3}\text{Nb}_{2/3})_3\text{O}_3$.
- 1 11. (Original) The sensor of claim 1 wherein the magnetostrictive layer is bonded to
2 the electroactive layer with non-conductive glue.
- 1 12. (Original) The sensor of claim 11 wherein the glue is non-conductive epoxy.
- 1 13. (Original) The sensor of claim 1 wherein the electroactive layer is a rectangular
2 prism having thickness, t , width, w , and length, l , with $t \leq w \leq l$ and three pairs of
3 opposing faces and wherein the electrodes are on one pair of opposing faces

4 and the magnetostrictive layer and a second magnetostrictive layer are bonded
5 to another pair of opposing faces.

1 14. (Original) The sensor of claim 13 wherein a third and a fourth magnetostrictive
2 layers are bonded to the third pair of opposing faces.

1 15. (Original) The sensor of claim 14 wherein the magnetostrictive layer is a
2 continuous piece wrapped around and bonded to two pairs of opposing sides and
3 the electrodes are on a third pair of opposing sides.

1 16. (Original) The sensor of claim 1 wherein the magnetostrictive layer is disk-
2 shaped

1 17. (Original) The sensor of claim 1, wherein the electroactive layer is a cylinder with
2 two circular faces and a side wall, the magnetostrictive layer is bonded to at least
3 one circular face and electrodes are on the side wall in an opposing relationship.

1 18. (Original) The sensor of claim 17 wherein the side wall has a circumference and
2 wherein the electrodes are arc-shaped, each electrode having an arc length of at
3 least $1/8$ and not greater than $3/8$ of the circumference of the side wall.

1 19. (Original) The sensor of claim 1 wherein the electroactive layer is a cylinder of
2 thickness, t , and diameter, d , and wherein $t \geq d$.

1 20. (Original) The sensor of claim 1 wherein the electroactive layer is a cylinder with
2 two circular faces of diameter d and a side wall of height h wherein $h \geq d$ and
3 wherein the electrodes are on the circular faces and the magnetostrictive layer is
4 bonded to the side wall.

1 21. (Original) The sensor of claim 1, wherein the electroactive layer forms a hollow
2 cylinder of length l , thickness t , and diameter, d where $t < d/2$ and $t \leq l$ and a pair
3 of opposing end faces.

1 22. (Original) The sensor of claim 21 wherein the electrodes are applied to an inner
2 cylinder surface and an outer cylinder surface.

1 23. (Original) The sensor of claim 22 wherein the magnetostrictive layer comprises a
2 cylinder of magnetostrictive material inserted into the hollow cylinder of
3 electroactive material.

1 24. (Original) The sensor of claim 21 wherein the electrodes are applied to the
2 opposing end faces.

1 25. (Original) The sensor of claim 21 wherein the magnetostrictive material layer
2 comprises a single piece of magnetostrictive material wrapped over, and bonded
3 to, an outer surface of the cylinder.

1 26. (Original) The sensor of claim 21 wherein the magnetostrictive material layer
2 comprises a single piece of magnetostrictive material wrapped over, and bonded
3 to, an inner surface of the cylinder.

1 27. (Original) A magnetic field sensor for sensing an external magnetic field, the
2 sensor comprising:

3 a layer of magnetostrictive material having a magnetization vector that
4 responds to the applied magnetic field by rotating in a plane and generating a
5 stress;

6 a layer of electroactive material mechanically bonded to the layer of
7 magnetostrictive material that responds to the stress by generating a voltage; and

8 means for measuring the voltage generated by the electroactive material
9 in a direction substantially parallel to the plane in which the magnetization vector
10 rotates.

1 28. (Original) The sensor of claim 27 wherein the electroactive layer is a rectangular
2 prism having thickness, t , width, w , and length, l , with $t \leq w \leq l$ and three pairs of
3 opposing faces and wherein the electrodes are on one pair of opposing faces
4 and the magnetostrictive layer and a second magnetostrictive layer are bonded
5 to another pair of opposing faces.

1 29. (Withdrawn) The sensor of claim 27 wherein the magnetostrictive layer forms a
2 hollow cylinder with an axis and a surface and the magnetostrictive layer has a
3 magnetization vector that changes orientation from circumferential to axial on the
4 surface of the cylinder in response to an external magnetic field applied in a
5 direction parallel to the axis.

1 30. (Withdrawn) The sensor of claim 27 wherein the electroactive layer forms a
2 hollow cylinder with an axis and a surface and wherein the magnetostrictive layer
3 is wrapped around and bonded to the surface and has a magnetization vector
4 that changes orientation from circumferential to axial on the surface of the
5 cylinder in response to an external magnetic field applied in a direction parallel to
6 the axis.

1 31. (Withdrawn) The sensor of claim 30 further comprising a second magnetostrictive
2 layer bonded to an inner surface of the hollow cylinder, wherein the second
3 magnetostrictive layer has a magnetization vector that changes orientation from
4 circumferential to axial on the surface of the cylinder in response to an external
5 magnetic field applied in a direction parallel to the axis.

32.-42. (Cancelled).

43. (Previously presented) An apparatus that responds to an external magnetic field, the apparatus comprising:

a layer of magnetostrictive material having a magnetization vector that responds to the magnetic field by rotating in response to the magnetic field and generating a magnetostrictive stress in a direction;

a layer of electroactive material, mechanically bonded to the layer of magnetostrictive material, that responds to the magnetostrictive stress by generating a voltage; and

electrodes across which appears the voltage generated by the electroactive material in a direction substantially parallel to the direction in which the principal magnetostrictive stress is generated.

44. (Currently amended) The apparatus of claim 43 wherein the magnetostrictive material is selected from the group consisting of amorphous-FeBSi, FeCoBSi alloys, polycrystalline nickel, iron-nickel alloys, iron-cobalt alloys and TbDyFe alloys ~~Terfenol-D®~~.

45. (Previously presented) The apparatus of claim 43 wherein the electroactive layer is a rectangular prism having three pairs of opposing faces and wherein the electrodes are on one pair of opposing faces and the magnetostrictive layer is bonded to one face of another pair of opposing faces.

46. (Previously presented) The apparatus of claim 45 further comprising a second magnetostrictive layer bonded to another face of the other pair of opposing faces.

47. (Previously presented) The apparatus of claim 45 wherein the magnetostrictive layer is a continuous piece wrapped around and bonded to two pairs of opposing sides and the electrodes are on a third pair of opposing sides.

48. (Previously presented) The apparatus of claim 43 wherein the magnetostrictive layer is disk-shaped

1 49. (Previously presented) The apparatus of claim 43, wherein the electroactive layer
2 is a cylinder with two circular faces and a side wall, the magnetostrictive layer is
3 bonded to at least one circular face and electrodes are on the side wall in an
4 opposing relationship.